

Attorney's Docket No.: 06618-662001
Client's Ref. No.: CIT 3252

OFFICIAL COMMUNICATION

FACSIMILE

FOR THE PERSONAL ATTENTION OF:

EXAMINER ALANDRA ELLINGTON

GROUP 2855 FAX NO: 703-872-9319

Number of pages including this page 45

Applicant : Yu-Chong Tai et al.
Serial No. : 09/900,743
Filed : July 6, 2001

Art Unit : 2855
Examiner : Alandra Ellington
Confirmation No.: 4560
FACSIMILE COMMUNICATION

Title : Surface-micromachined pressure sensor and high pressure application

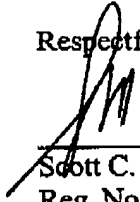
Commissioner for Patents
Washington, D.C. 20231

Sir:

Attached to this facsimile communication cover sheet is a Response to Final Office Action, faxed this 22nd day of August, 2002, to Group 2855, the United States Patent and Trademark Office.

Respectfully submitted,

Date: August 22, 2002



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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Yu-Chong Tai et al. Art Unit: 2855
Serial No.: 09/900,743 Examiner: Alandra Ellington
Filed : July 6, 2001 Confirmation No.: 4560
Title : SURFACE-MICROMACHINED PRESSURE SENSOR AND HIGH
PRESSURE APPLICATION

#601A
T. Yang
8-2702

BOX AF

Commissioner for Patents
Washington, D.C. 20231

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RESPONSE

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In response to the official action mailed 05/22/02, paper
no. 2 in the above referenced case, please amend the application
as follows:

In the specification:

Please replace the paragraph beginning at page 4, paragraph
number [0023] with the following rewritten paragraph:

Figure 1 shows a cross-section of the surface micromachined
piezoresistive high-pressure sensor according to an embodiment.
Strain sensitive resistors 102, such as polysilicon
piezoresistors, may be placed in a location where they are
sensitive to the strain caused by diaphragm movement. Other
materials, such as platinum, can also be used. In a cross-
section, strain sensitive resistors 102, 104 are shown within a

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August 22, 2002

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